

ION SOURCES AND METHODS FOR GENERATING ION BEAMS WITH CONTROLLABLE ION CURRENT DENSITY DISTRIBUTIONS OVER LARGE TREATMENT AREAS

Abstract

The presently disclosed ion sources include one or more electromagnets for changing the distribution of plasma within a discharge space of an ion source. At least one of the electromagnets is oriented about an outer periphery of a tubular sidewall of the ion source and changes a distribution of the plasma in a peripheral region of the discharge space.

FIGURE 1A